## **REMARKS**

The above amendment corrects an obvious omission in new claim 12.

Respectfully submitted,

Hideo HADA et al.

By: Matthew Jacob

Registration No. 25,154 Attorney for Applicants

MJ/gtg Washington, D.C. 20006-1021 Telephone (202) 721-8200 Facsimile (202) 721-8250 November 27, 2002

Claim 12 has been amended as follows:

- 12. (Amended) A positive-working photoresist composition which comprises, as a uniform solution in an organic solvent:
- (A) 100 parts by weight of a resinous compound capable of being imparted with increased solubility in an aqueous alkaline solution by interaction with an acid;
- (B) from 0.5 to 30 parts by weight of a radiation-sensitive acid generating compound capable of generating an acid by irradiation with a radiation; and
  - (C) an organic solvent in an amount sufficient to dissolve the components (A) and (B), the component (A) being a copolymer consisting of the monomeric units of
- (a1) from 30 to 60% by moles of 2-alkyl-2-adamantyl (meth) acrylate units having the formula:

in which R<sup>1</sup> is a hydrogen atom or a methyl group and R<sup>2</sup> is an alkyl group having 1 to 4 carbon atoms.

(a2) from 20 to 50% by moles of 2-oxooxapentyl (meth) acrylate units having the formula:

in which R<sup>1</sup> is a hydrogen atom or a methyl group,

(a3) from 20 to 40% by moles of 1-hydroxyadamantyl (meth) acrylate units.